



Software solutions for
optimizing micro & nano
fabrication processes



Final Announcement

BEAMeeting Munich 2023 Technical Workshop & Discussion



Time: Tuesday, March 14th, 2023 9:00 – 12:15 CET Training
13:30 – 17:30 CET BEAMeeting
Wednesday, March 15th, 2023 9:00 – 12:30 CET BEAMeeting
14:00 – 16:30 User Workshop

Location: Munich – [Hotel Holiday Inn Munich - Unterhaching](#)
Online via TEAMS (access data will be sent after registration shortly before the BEAMeeting)

BEAMeetings are a technical exchange platform for the direct write community focused on e-Beam and laser lithography, data-preparation, PEC, process correction, and lithography simulation. It is a platform for BEAMER users and those who are interested in GenISys software. As in the past, it is a great opportunity to **meet with the GenISys team**, have **face to face in-depth discussions**, **exchange ideas** and **position your needs and wishes**.

The first day of the BEAMeeting on March 14th will start with two **Training Workshops**, one discussing **layout operations** and the other one on **proximity effect correction**. In the afternoon of March 15th there will be an interactive **User Workshop**. Please prepare your technical questions for these sessions.

Please save the date in your calendar and register our BEAMeeting:

On-Site in Munich – [REGISTER here](#)
Online via TEAMS – [REGISTER here](#)

or visit our Homepage for the details: [BEAMeeting Munich March 2023](#).

The BEAMeeting is free of charge. Please feel free to share this information with interested colleagues who may wish to join the BEAMeeting.

Please do not hesitate to contact us (marketing@genisys-gmbh.com) if you have any questions or any suggestions.

We are looking forward to presenting you with an interesting and valuable workshop!

Thank you,
The GenISys Team

Munich BEAMeeting AGENDA

	Tuesday, March 14th	Start
Training Jörg Günther / Aditya Reddy	Session 1: BEAMER – Layout Operation and Fracturing	09:00
	Coffee Break	10:30
Training Jörg Günther / Aditya Reddy / Daniel Ritter	Session 2: Proximity & Process Calibration and Correction	10:45
	Lunch Break	12:15
Nezih Ünal / Uli Hofmann GenISys	Welcome & GenISys Update	13:30
Prof. Ali W. Elshaari KTH	Topological invariants in 1D photonic lattices	14:00
Aditya Reddy / Qing Tan GenISys	LAB – process analysis for proximity applications	14:30
	Coffee Break	15:00
Sven Bauerdick GenISys	ProSEM Update: General and SEM Automation	15:30
Sven Bauerdick GenISys	Application Use Cases of ProSEM	16:00
(Development / Application) GenISys	BEAMER in-sides on solving intriguing application problems: Case study	16:30
Stephan Martens IMS Chips	TRACER process calibration	17:00
	Closing	17:30
	Dinner - Dolce e Salato	18:00
	Wednesday, March 15th	
Dmitry Titko GenISys	Pattern fidelity for plasmonics	9:00
Sukanya Mahapatra C2N (Paris)	A nanophotonic platform for strong interaction of photons with cold atoms	9:30
Aditya Reddy / Nikola Belic GenISys	T-Gate correction: Present and Prospect	10:00
	Coffee Break	10:30
Daniel Ritter GenISys	Data preparation for high density gratings	11:00
Silvia Diewald KIT	Creating patterns with the Python module using external libraries	11:30
Thomas Michels GenISys	BEAMER Update Development Roadmap and Discussion Needs & Wishes	12:00
	Lunch Break	12:30
	User Workshop	14:00
	Coffee Break	15:30
	Open Discussion	16:00
	Closing	16:30